

Amendments to the Claims

1. (Currently Amended) A vacuum deposition apparatus comprising:
a susceptor for heating a glass substrate a portion of the susceptor providing an area used as a sliding portion on which to slide the glass substrate to a desired position the susceptor being used for generating plasma;
a lift pins for supporting said the glass substrate on the susceptor;
a robot arm for transferring the glass substrate onto the susceptor to and returning the glass substrate from the susceptor; and
a stopper pin for indicating an end of the susceptor; and
a groove formed in said portion a slide part of the susceptor for receiving and into which a film-forming material scraped from a surface of the susceptor by a leading edge of the glass substrate during sliding of is generated by friction between the substrate and the susceptor when the substrate is inclined for placing the glass substrate on the surface of the susceptor.

2. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein a gap between an end a beginning of said portion of said substrate and said groove stopper pin is at least 3 mm, the beginning of said portion being the position on the susceptor where the leading edge of the glass substrate first touches the susceptor during sliding.

3. (Currently Amended) The vacuum deposition apparatus according to claim 2, wherein the said gap is 10 mm.

4. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the susceptor is made of a quartz material.

5. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the section of said groove formed in the slide part sliding portion has a polygonal configuration.

6. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the bottom face of the groove formed in the slide part sliding portion has a curved configuration.

7. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the bottom face of the groove formed in the slide part sliding portion includes an incline plane and a perpendicular plane.

8. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the groove formed in the slide part sliding portion has a V-shaped configuration.